

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: N. MISE, et al.

Application No.: Rule 1.53(b) Divisional of U.S. Patent Application Serial
No. 09/890,611, filed October 11, 2001

Filed: On even date herewith

For: ION CURRENT DENSITY MEASURING METHOD AND
INSTRUMENT, AND SEMICONDUCTOR DEVICE
MANUFACTURING METHOD

Art Group of Parent: 2812

Examiner of Parent: A. C. Stevenson

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

October 31, 2003

Sir:

Prior to examination, please amend the above-identified application as listed
below and as set forth on the following pages:

Amendments to the Specification and

Remarks are included following the amendments.